

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant	: Satoru Okamoto	Art Unit	: 1765
Serial No.	: 10/689,617	Examiner	: Lan Vinh
Filed	: October 22, 2003	Confirmation No.:	4799
Title	: METHOD FOR CLEANING PLASMA ETCHING APPARATUS, METHOD FOR PLASMA ETCHING, AND METHOD FOR MANUFACTURING SEMICONDUCTOR DEVICE		

**Mail Stop Amendment**

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

AMENDMENT IN REPLY TO ACTION OF MARCH 8, 2006

Please amend the above-identified application as follows:

**Amendments to the Claims** are reflected in the listing of claims that begins on page 2 of this paper.

**Remarks/Arguments** begin on page 25 of this paper.